

# Light Waves as Standard of Length



ME 338: Manufacturing Processes II  
Instructor: Ramesh Singh; Notes: Profs. Singh/Kurfess

# Light Waves

- Wave Model of Light
- Introduction to Interference
- Interferometry Applied to Flatness Testing
- Additional Interferometry Applications
- Interferometers.



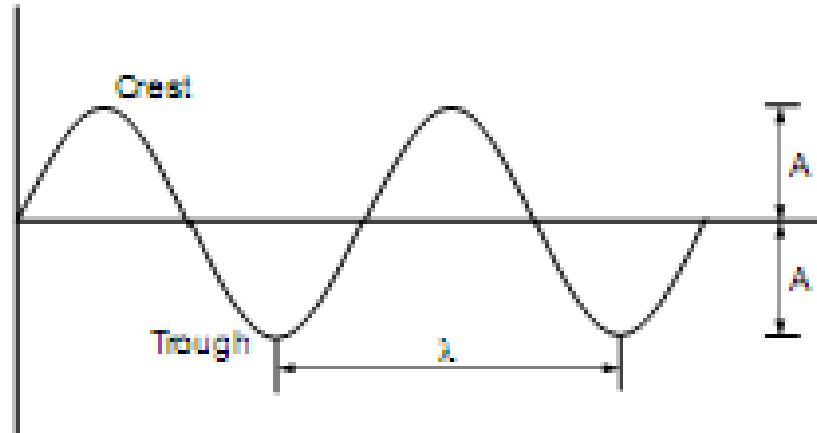
# History

## Christiaan Huygens (1629-1695)

- First major proponent of the wave theory of light
- Considered light as a wave motion propagated in ether



# Light Wave



A = Amplitude

$A^2$  = Intensity

$\lambda$  = Wave Length

$V = \lambda/T$  = Velocity of Transmission

$n=1/T$  = Frequency



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# Light Waves as Standards-Benefits

- High Degree of Accuracy
  - Used by the International Committee of Weights and Measures
  - Meter is defined as:  $1,650,763.73\lambda$
  - $\lambda$  = Wavelength of the orange-red isotope of Krypton 86 (605.78 nm)
  - Subdivision to 1 part per million
- Virtually Independent of Ambient Conditions
  - Temperature
  - Pressure
- Reproducible
  - No need for a physical standard artifact.



# Light Sources

## Krypton 86 (605.78 nm)

- Excitation takes place at very low temperatures ( $\sim 68$  °K)
- Used as International Standard of Length

## Mercury 198 (546.1 nm)

- Less expensive
- Green light easily separated with filters
- Drawback – radiates a mixture of wavelengths

## Cadmium (644.85 nm)

- (Almost) symmetrical red spectral line
- Official secondary standard of length

## White light ( $\sim 500$ nm).



# Light Sources

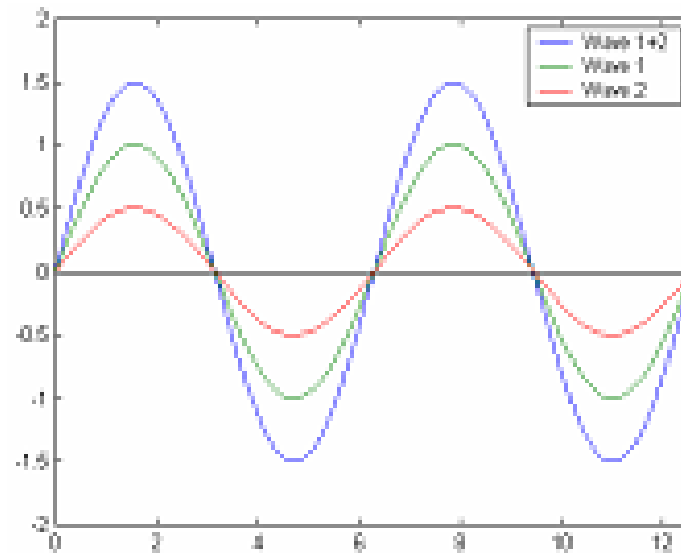
- Gas Lasers
  - Helium – Neon (632.8 nm)
  - CO<sub>2</sub> – (10600 nm)
- Gas Lasers - advantages
  - Produce highly monochromatic light
  - Highly intense (1000 times more intense than others)
  - Created by exciting a mixture of neon and helium in a special discharge tube
- Gas Lasers - disadvantages
  - High cost
  - Wavelength affected by temperature and vibration
  - Special optics required to spread the ray.



# Interference- Basics

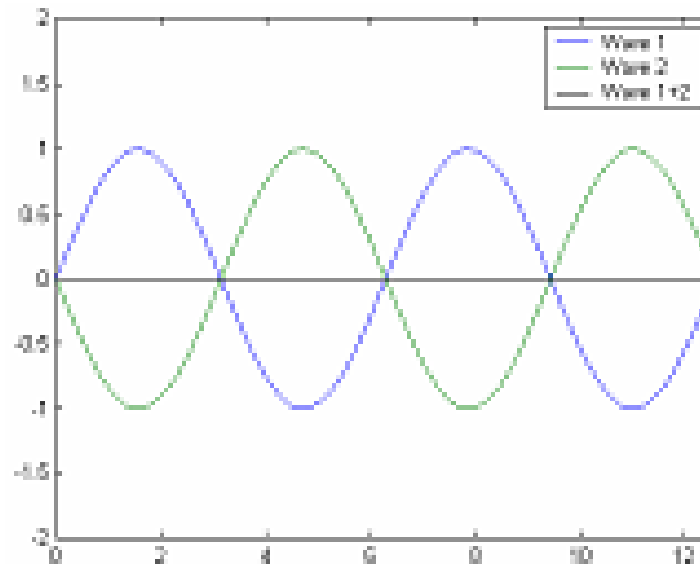
Consider Two Monochromatic Rays

When the two waves are in phase, they add:



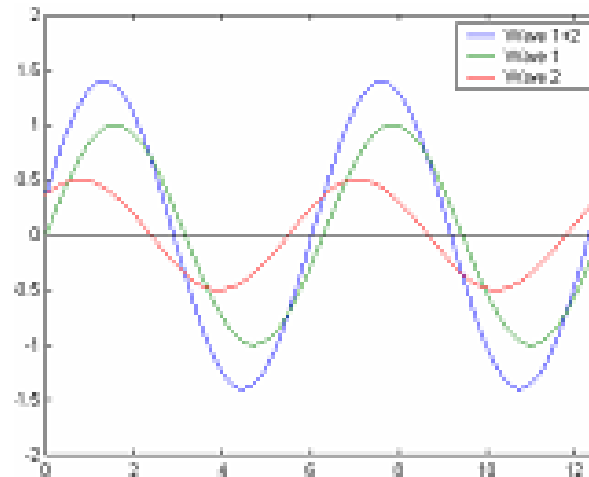
# Interference- Basics

When they are  $180^\circ$  out of phase, they cancel.



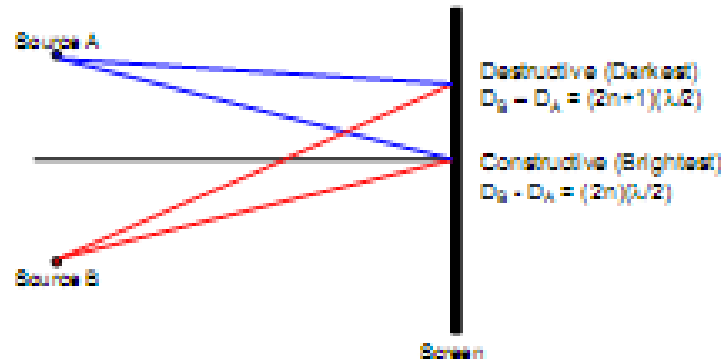
# Interference-Basics

- The resultant wave will equal the sum of the amplitudes( $R = A1 + A2$ )



# Fringes

- Consider rays from two point sources, A & B



- The difference in the path lengths creates light and dark bands
  - Difference of odd number of half wavelengths: destructive
  - Difference of even number of half wavelengths: constructive



# Fringe Formation

- In order for light interference to occur, the following conditions are necessary:
  - Light from a single source must be divided into two component rays
  - Before being re-combined at the receiver, the components must travel paths whose lengths differ by an odd number of wavelengths
  - Note, this is a relative measure



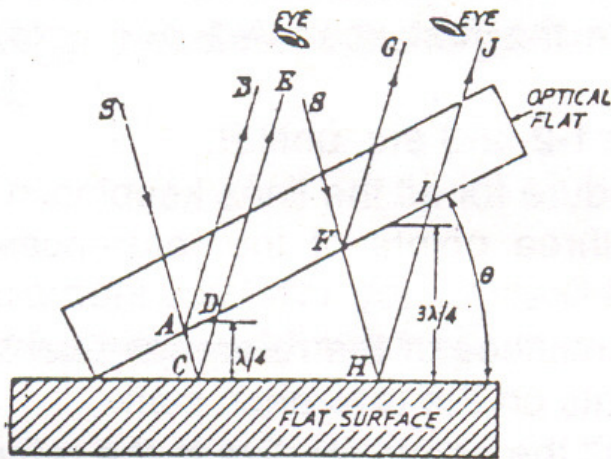
# Using Interference for Flatness Testing

- Optical Flat
  - A circular piece of stress free glass or fused quartz
  - Has two planes that are flat and parallel
  - Surfaces are finished to an optical degree of flatness
- Properties of the Optical Flat
  - Vary in size from 25 mm to 300 mm diameter
  - Minimum expansion due to heat
  - Thickness (up to 50 mm) insures freedom from distortion.



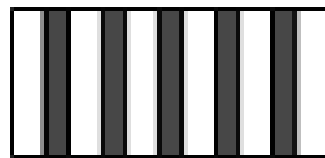
# Optical Flat

- Interference in an optical flat



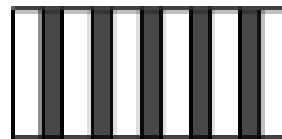
# Using Interference for Flatness Testing

- Place an Optical Flat on the surface
  - Will lie at a small angle to the surface due to air cushion
- Illuminate with monochromatic light
- Will observe fringes like those shown below
  - Dark fringes occur for  $(1/2 + n)\lambda$ ,  $n = 1, 2, 3, \dots$
  - Light fringes occur for  $n\lambda$ ,  $n = 1, 2, 3, \dots$



# Using Interference for Flatness Testing

- As the angle is increased, the fringes are brought closer together
- As the angle is decreased, the fringes spacing increases
- Each adjacent fringe represents a change in elevation of  $\lambda/2$
- Total change in elevation =  $\lambda/2 * n$



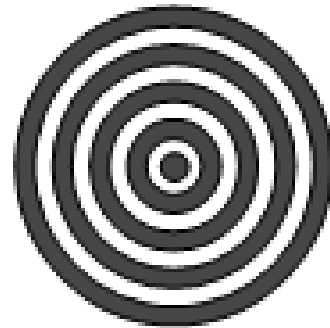
# Errors

- The line of sight should be perpendicular to the reference surface of the optical flat.
- Fringe spacing will be distorted
  - A viewing error of  $30^\circ$  results in an error of 15%
  - A viewing error of  $45^\circ$  results in an error of 40%



# Convex / Concave Surfaces

- A convex or concave surface will result in concentric fringes, as shown below
- To determine which, apply pressure to optical flat



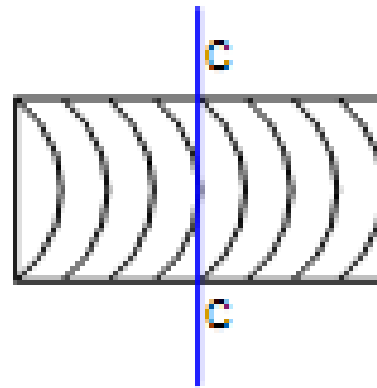
# Practice for Using Optical Flats

- Handle optical flats carefully
- Handle optical flats minimally
- Ensure optical flat and work surface are clean by using a lint free soft cloth
- Never wring an optical flat to a surface
  - do not push hard on an optical flat
- Never wring two optical flats together.



# Convex / Concave Surfaces

- In the following figure, the edge is half a wavelength higher/lower than the centerline



# Drawbacks of Using Optical Flats

- Difficult to control the lay of the flat
  - difficult to orient the fringes to their best advantage
- Fringe pattern not viewed from directly above can cause distortion and generate errors.



# Optical Flat with Fringes

8 inch Zerodur, 3/10

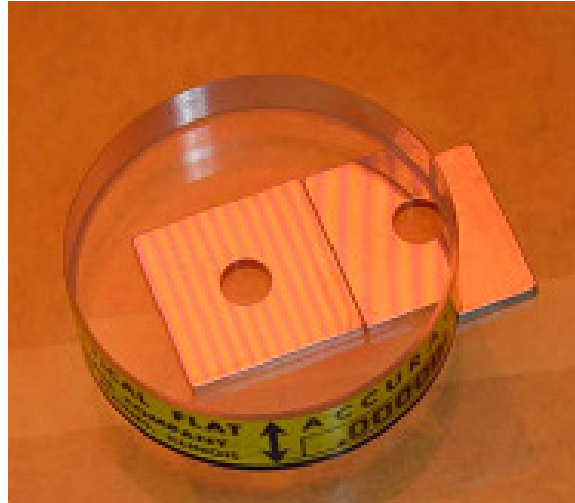


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# Two Flats

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Difference in heights is 0.0001 ( $\pm 2\mu\text{in}$  WRT calibration)



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# Flat's in Operation

Pushing on a Flat

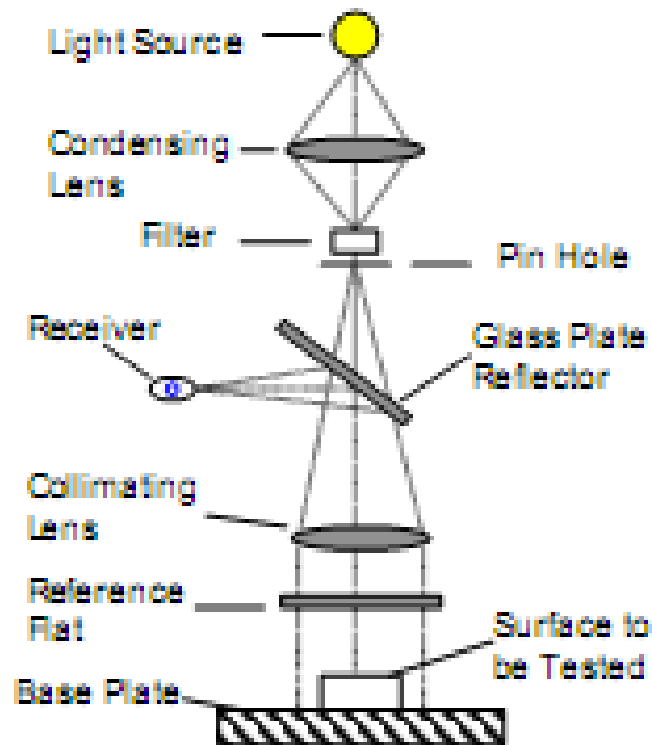


Pivot Points

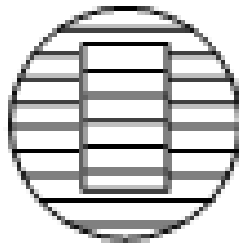


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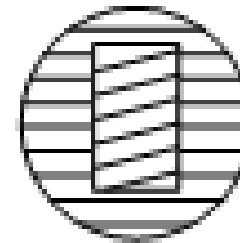
# Interferometers for Flatness Testing



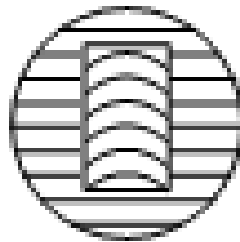
# Interferometers for Flatness Testing



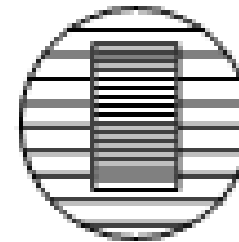
Surface flat & parallel



Surface flat but not parallel from left to right



Surface convex or concave



Surface flat but not parallel from top to bottom



# Interferometers

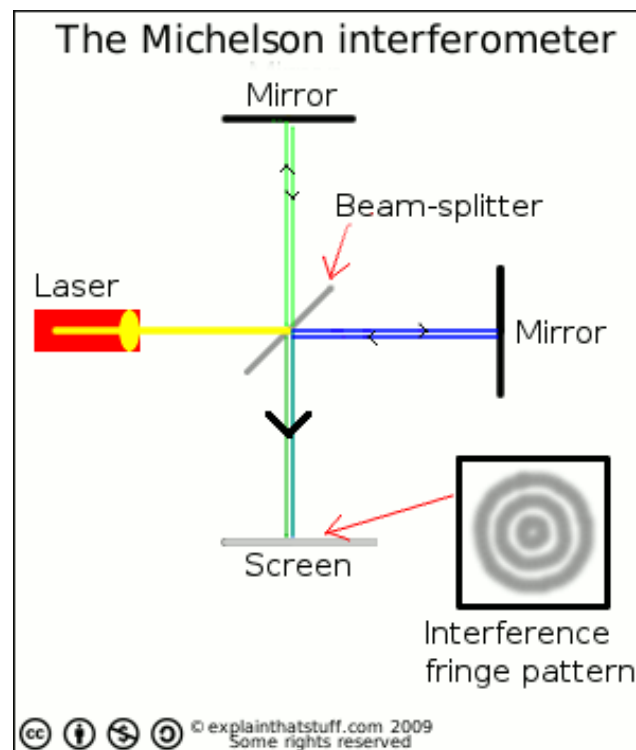
- Michelson Interferometer
- Wyko NT9100 3-D Surface Profiler
- Laser Interferometer



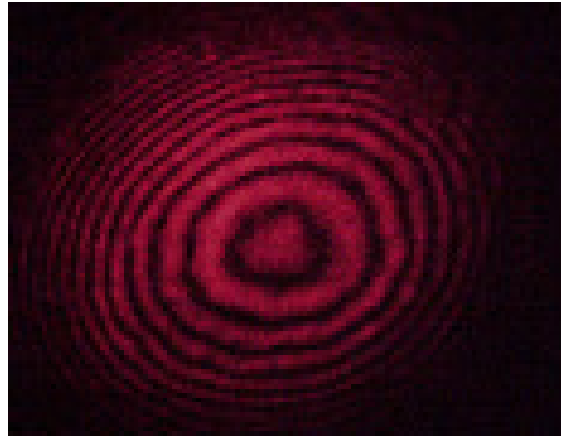
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# Michelson Interferometer

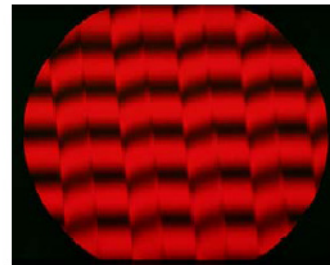
- Compares the path lengths of light traveling two different directions



# Michelson Interferometer



Red Light



Profile



- Used for examining minute details of surfaces
- Used by Michelson to disprove the theory of ether



# WYKO NT9100



Z- Resolution – 0.01 nm

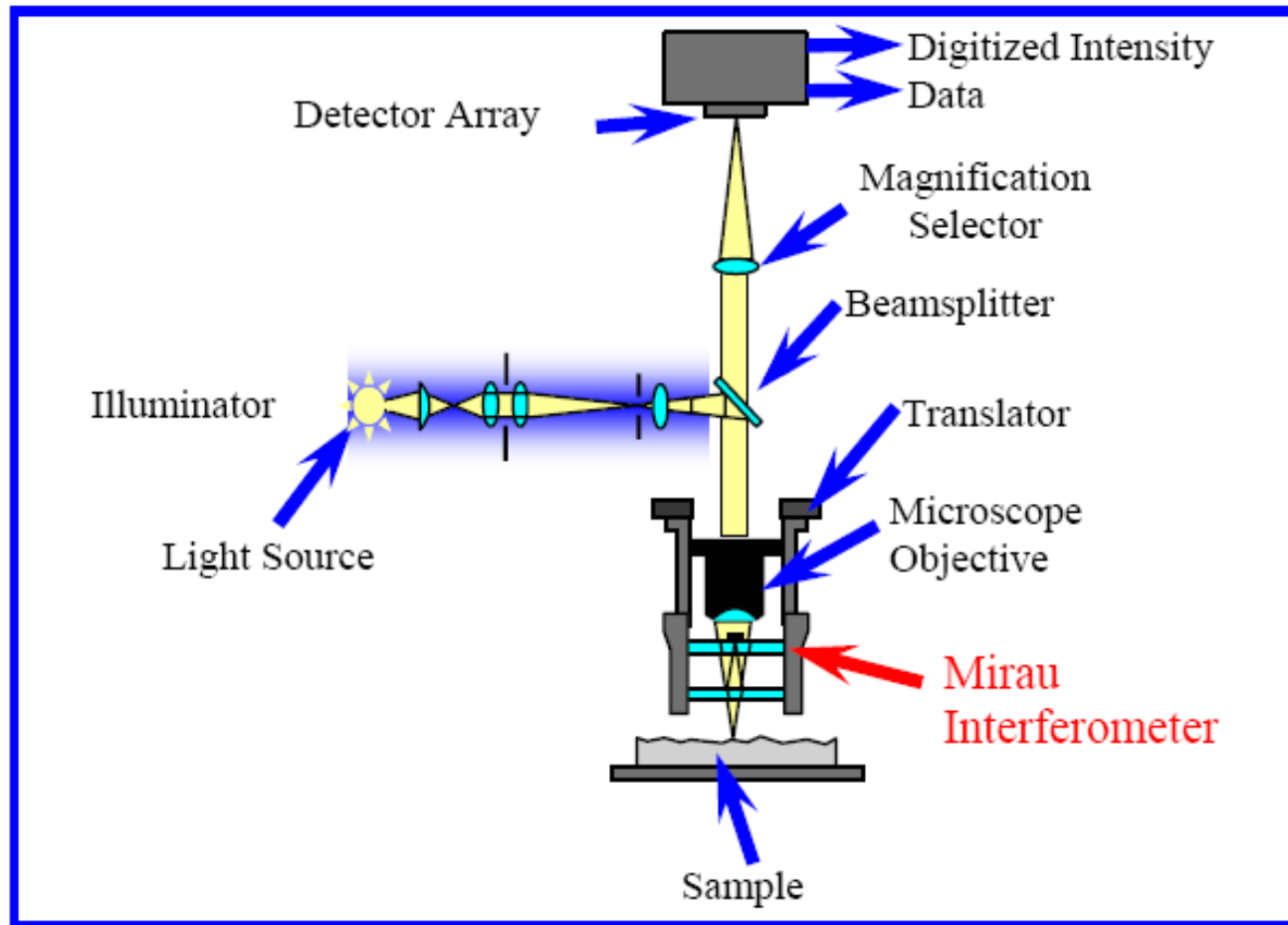
Scan length – 10 mm

Lateral resolution – 1  $\mu\text{m}$



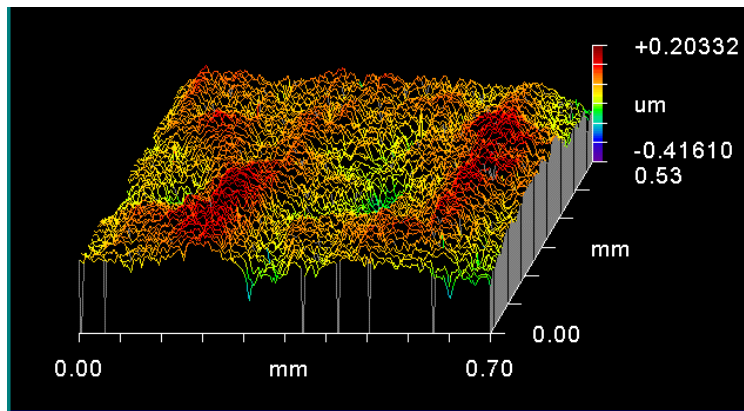
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# Interferometry-Basics

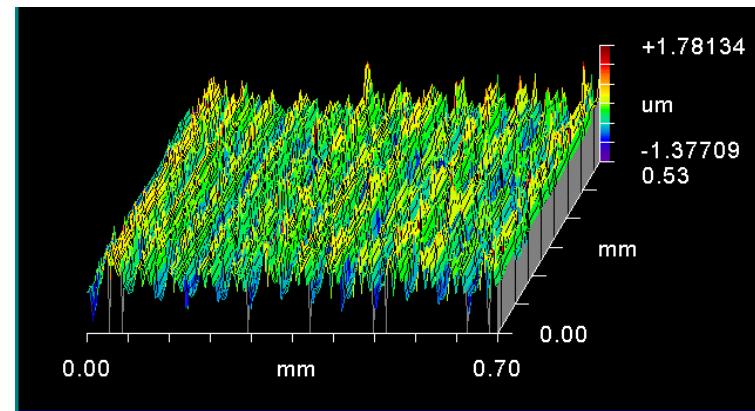


# Plots from Whitelight Interferometer

Periodic and/or random deviations of a real surface from the nominal surface (texture)

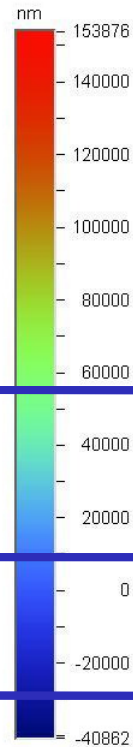
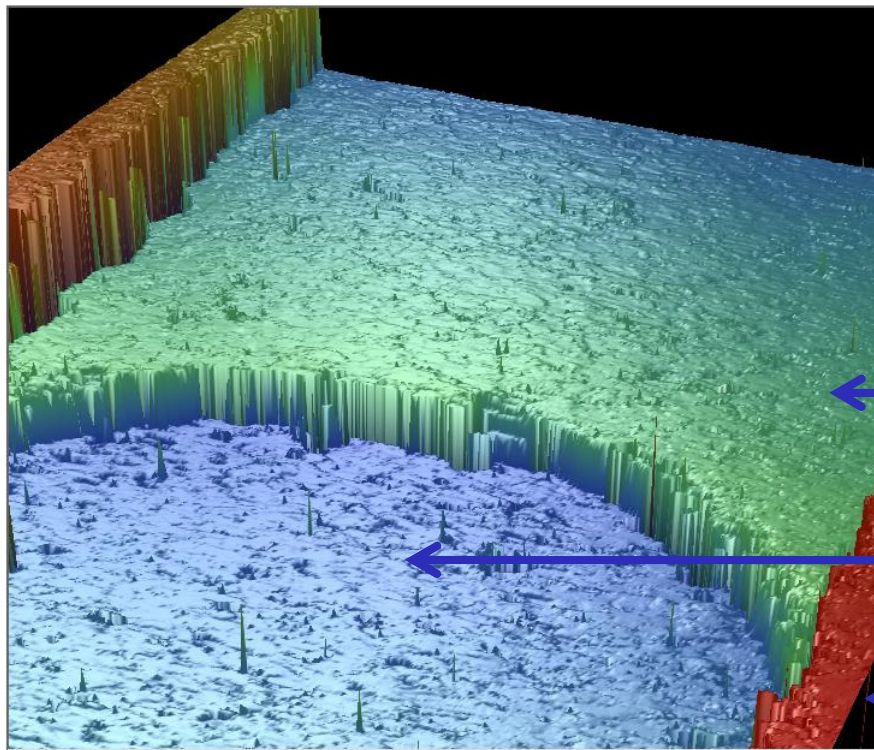


Isotropic Surface: random



Turned Surface: Periodic





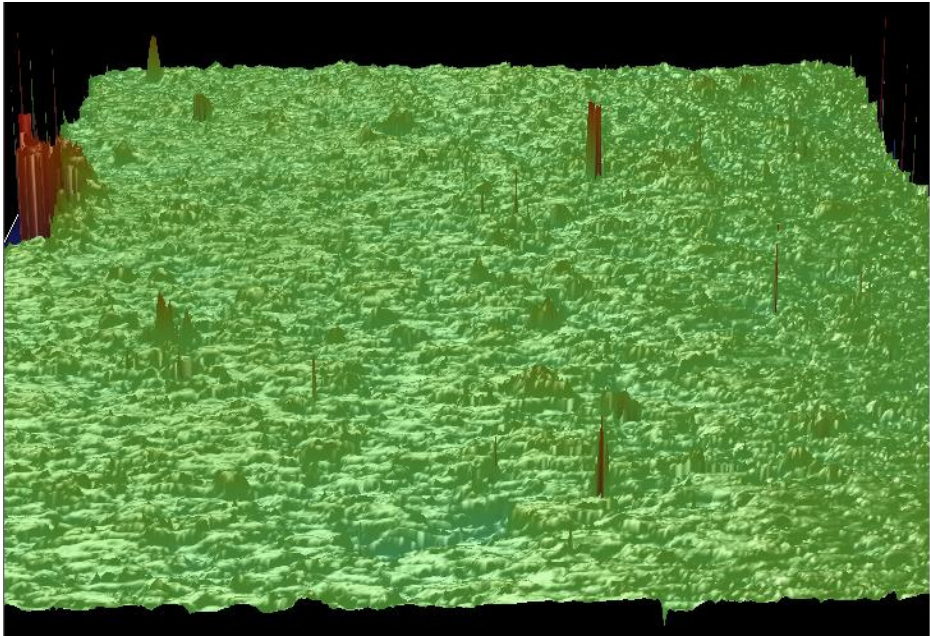
3D groove height (other fresh groove)

Reference surface

Machined surface

Top surface

Surface morphology of groove bottom surface

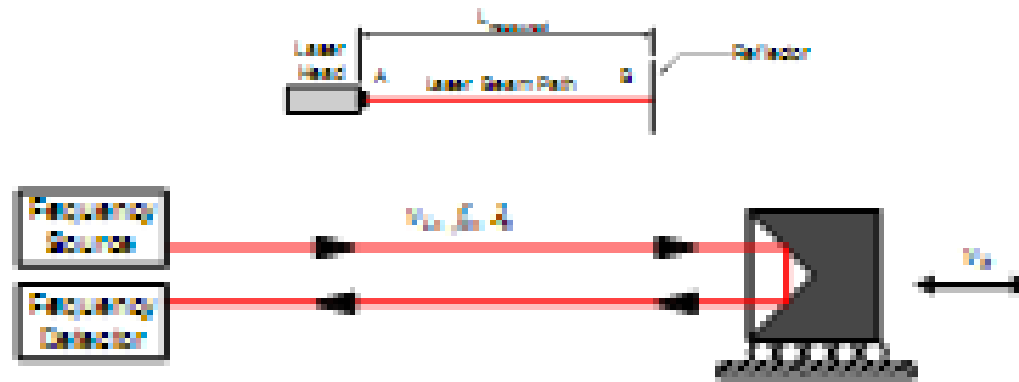


# Laser Interferometer

- Counts the number of wavelengths that the laser traverses between the two points to determine distances
  - Measures only relative displacements
- Can be used to measure:
  - Linear Displacement
  - Angular Displacement
  - Straightness
  - Squareness
  - Parallelism



# Laser Interferometer



$v_L$ : Wave Velocity

$v_R$ : Reflector Velocity

$f_0$ : Wave frequency

$\lambda_0$ : Wavelength

$\Delta\phi$ : Position Shift

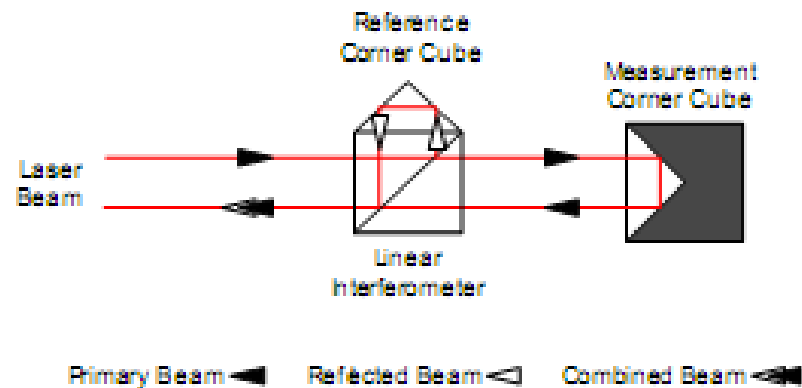
$\Delta x$ : Position shift

$$\Delta x = \Delta\phi \lambda / 4\pi$$



# Laser Interferometer

- Typical laser path



- The accuracy of the interferometer is determined by the laser wave length, which is known to better than 0.05 parts per million.

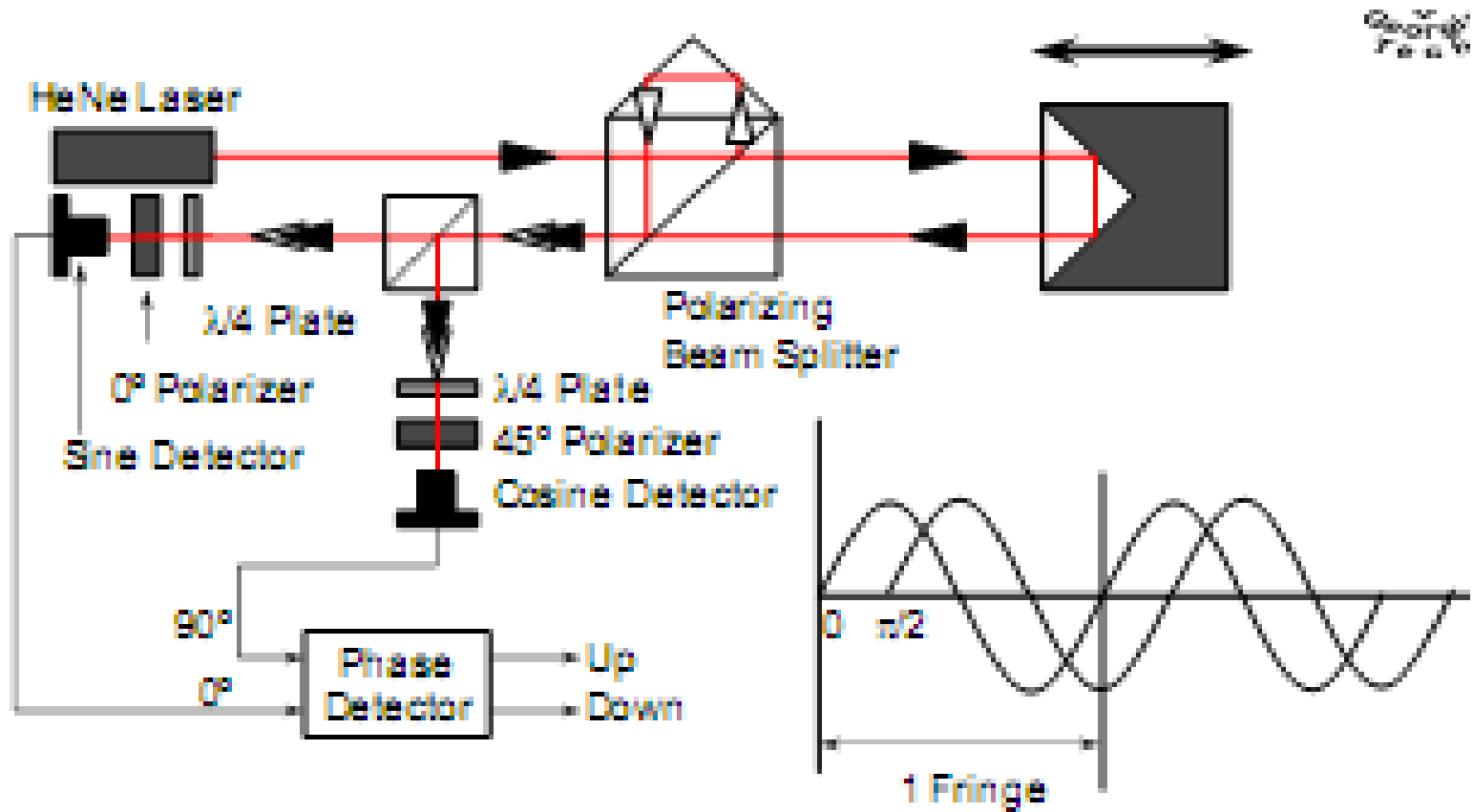


# Improvements

- Phase Detection
  - Michelson interferometer 1/8 resolution, easily
  - Can take half the signal and retard it by 90 phase
  - Using a quarter wave plate
  - First detector and second detector generate sine and cosine components.



# Improvements



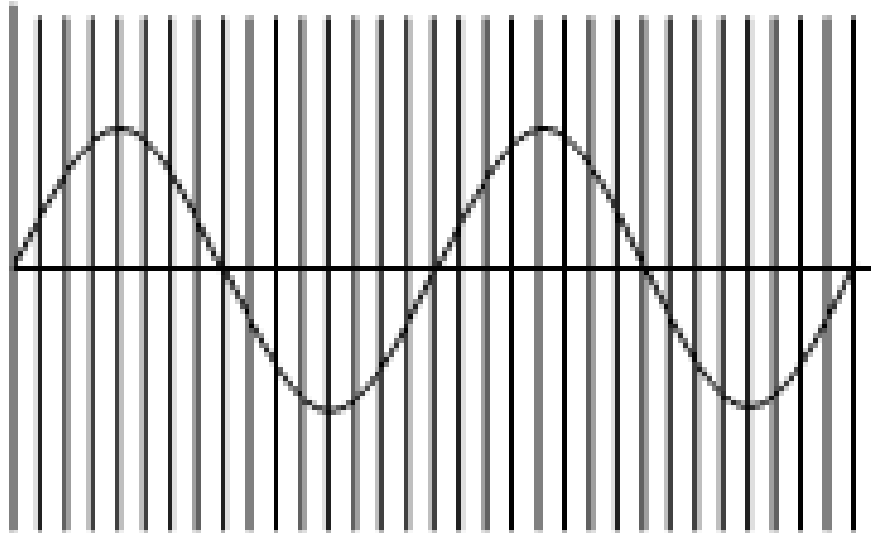
Primary Beam Reflected Beam Combined Beam

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# Subdividing –Expanding Resolution

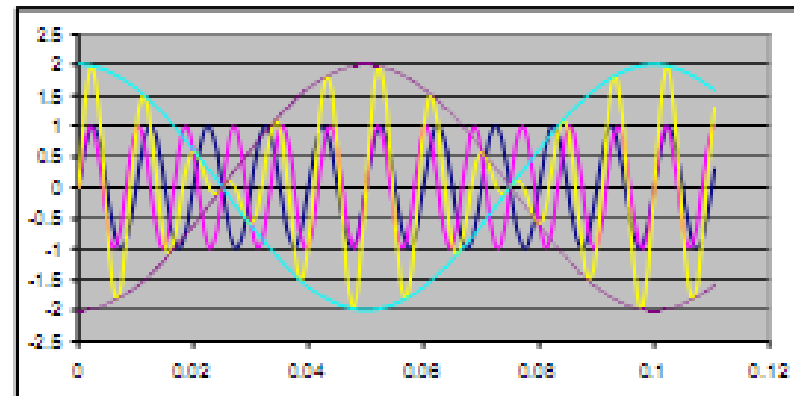
- Sine and cosine detector output follow a predictable sinusoidal curve
- Common resolution interpolators 16X to 256X



# Improvements-Hetrodyne lasers

- As target moves faster, fringes occur faster and Doppler effects become significant
- Using a dual frequency laser with a slight variation in frequencies (20 MHz) one can generate a beat frequency.

$$Y_1 = A \cos(2\pi f_1 t) \quad Y_2 = A \cos(2\pi f_2 t)$$
$$Y_1 + Y_2 = A \cos\left(\frac{2\pi(f_2 - f_1)t}{2}\right) \cos\left(\frac{2\pi(f_1 + f_2)t}{2}\right)$$
$$f_{\text{waveform}} = \frac{f_1 + f_2}{2} \quad f_{\text{amplitude}} = \frac{f_2 - f_1}{2}$$



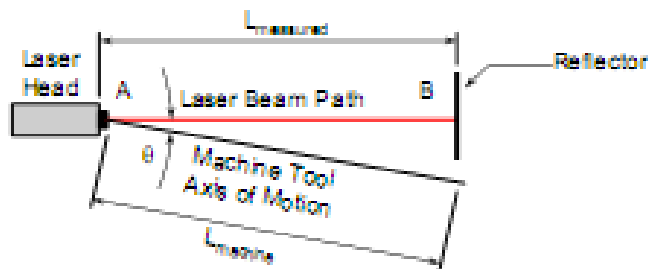
# Laser Interferometry - Cosine Error

- Definition
  - the measurement error in the motion direction caused by angular misalignment between a linear displacement measuring system and the gate of displacement being measured
  - cosine errors are present when comparing any 2 displacement measuring systems
- Assuming perfect laser (or artifact) and machine
  - a laser angular misalignment causes the laser to always display a smaller or shorter value than the machine's display
  - an angular misalignment of an artifact of length standard causes the machine's display to always be longer than the artifact's length



# Laser Interferometry - Cosine Error

- Misalignment of the laser beam path to the axis of motion of the machine tool with results in an error between the measured distance and the actual distance traveled



$$L_{measured} < L_{machine}$$
$$L_{measured} = L_{machine} \cos(\theta)$$



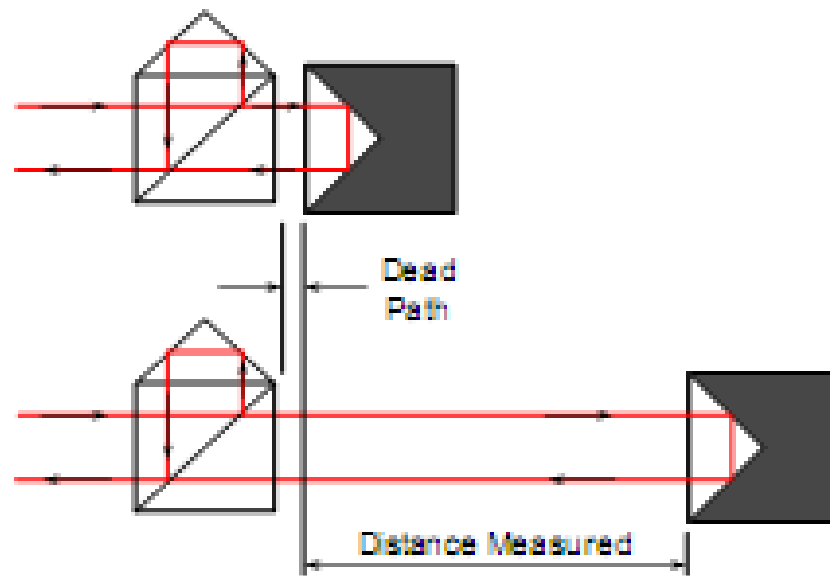
# Environmental Conditions

- In making linear measurements, it is necessary to compensate for:
  - the change in wave length of the laser light due to the ambient conditions of the air (VOL)
  - The change in length of the machine's scales due to thermal expansion or contraction



# Laser Dead Path

- The compensation for velocity-of-light (VOL) error is applied only to the portion of the path where displacement is measured



# Summary

- Interferometry
- Laser Interferometer
- White Light Interferometer
- Errors



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